



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Confirmation No.: 7420

Takaei SASAKI et al.

Group Art Unit: 1746

Serial No.: 10/706,944

Examiner: Michail Kornakov

Filed: November 14, 2003

Attorney Docket No.: 101136-00103

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE  
PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS  
AND METHOD FOR THE PREPARATION THEREOF, AND  
SEMICONDUCTOR CIRCUITS AND METHOD FOR THE  
FABRICATION THEREOF

**AMENDMENT UNDER 37 CFR §1.111**

**Mail Stop Amendment**

Director for the U.S. PTO

P.O. Box 1450

Alexandria, VA 22313-1450

Date: June 7, 2004

Sir:

In reply to the outstanding Office Action dated April 22, 2004, please amend the  
application as shown on the following pages: